

Notice of References Cited

Application/Control No.

10/711,779

Applicant(s)/Patent Under
Reexamination
LIU, CHI-YUAN

Examiner

VAN T. PHAM

Art Unit

2627

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,796,704	08-1998	Nanba et al.	369/53.12
*	B	US-6,331,966	12-2001	Minami et al.	369/13.07
*	C	US-7,126,896	10-2006	Miyaki, Seiichiro	369/47.53
*	D	US-5,274,622	12-1993	Kono, Mutsumi	369/116
*	E	US-6,741,529	05-2004	Getreuer, Kurt W.	369/30.17
*	F	US-5,878,015	03-1999	Schell et al.	369/116
*	G	US-2003/0169659	09-2003	Miyaki, Seiichiro	369/47.53
*	H	US-6,671,232	12-2003	Stupp, Steven E.	369/13.02
*	I	US-6,996,381	02-2006	Lee, Chung Hee	455/115.1
*	J	US-5,675,568	10-1997	Hajjar et al.	369/47.51
*	K	US-6,901,039	05-2005	Sugie et al.	369/47.28
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.